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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

: **Mail Stop: ISSUE FEE**

Shoriki NARITA et al.

: **Confirmation No. 1853**

Serial No. 10/019,700

: [Group Art Unit 2825]

Filed January 2, 2002

: Examiner Igwe U. Anya]

BUMP FORMING APPARATUS FOR
CHARGE APPEARANCE SEMICONDUCTOR
SUBSTRATE, CHARGE REMOVAL METHOD
FOR CHARGE APPEARANCE SEMICONDUCTOR
SUBSTRATE, CHARGE REMOVING UNIT FOR
CHARGE APPEARANCE SEMICONDUCTOR
SUBSTRATE, AND CHARGE APPEARANCE
SEMICONDUCTOR SUBSTRATE

RESUBMISSION OF REFERENCES

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

Applicants note that the Submission of References dated September 20, 2004 contained a typographical error. Specifically, the date of reference JP 2002009569 should be 01/2002 not 01/2001. Below is a corrected listing of the previously submitted references.

USP 6,198,616, 03/2001, Dahimene et al.
JP 01077111, 03/1989 (Abstract)
JP 2002009569, 01/2002 (Abstract)
JP 2002203995, 07/2002 (Abstract)

Respectfully submitted,

Shoriki NARITA et al.

By

W. Douglas Hahn

Registration No. 44,142

Attorney for Applicants

WDH/gtg
Washington, D.C. 20006-1021
Telephone (202) 721-8200
Facsimile (202) 721-8250
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